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08/18/2008

RESPONSE UNDER 37 CFR 1.116 EXPEDITED PROCEDURE EXAMINING GROUP 2624

> PATENT APPLICATION Docket No.: 2522-047 Client Ref. No. AW8085US/EK

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Deok-Yong KIM et al.

Serial No.: 10/749,670 Examiner: Rosario, Dennis

Filed: December 30, 2003 Art Unit: 2624

Confirmation No.: 9761

For: METHOD AND APPARATUS FOR DETECTING DEFECTS ON A

WAFER

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## **AMENDMENT AFTER FINAL REJECTION UNDER 37 CFR 1.116**

Responsive to the Final Office Action, Paper No. 20080512, dated May 20, 2008, please amend the application as follows.

- Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.
- Remarks/Arguments begin on page 7 of this paper.